2020년 2월 14일(금), 10:45~12:30
Room H (하트 I, 6층)

Q. Metrology, Inspection, and Yield Enhancement 분과
[FH2-Q] Metrology, Inspection, and Yield Enhancement

FH2-Q-1 **10:45~11:15**	**[초청]** **High-Resolution Inspection System based on Field Emission X-Ray Source for Non-Destructive Testing** Jehwang Ryu[1], Amar Prasad Gupta[1], Wooseob Kim[1], Han Gyeol Park[2], Seung Jun Yeo[2], Jaekyu Jang[2], Jaeik Jung[2], Jung Sun Ahn[1], and Seung Hoon Kim[3] *[1]Kyung Hee University, [2]CAT Beam Tech Co., Ltd., [3]Asan Medical Center*
FH2-Q-2 **11:15~11:45**	**[초청]** **MAPS(Multi-axis Absolute Position-posture Sensor) and Smart Stage** Jae Wan Kim[1] and Jong-Ahn Kim[2] *[1]Batugem Co., Ltd., [2]KRISS*
FH2-Q-3 **11:45~12:00**	**변형거울을 이용한 Standalone TSOM 광학계 개발** 유병건, 이대열, 박준성, 이준호 *Department of Optical Engineering, Kongju National University*
FH2-Q-4 **12:00~12:15**	**Deep Learning Based Wafer Edge Defect Detection System** Gil-Jun Lee[1,2], Jee-Hyong Lee[3], and Simon S. Woo[2] *[1]MEMC Korea Co., Department of Applied Data Science, Sungkyunkwan University, [2]Department of Applied Data Science, Sungkyunkwan University, [3]Department of Computer Science, Sungkyunkwan University*
FH2-Q-5 **12:15~12:30**	**EUV Ptychography Microscope를 이용한 Through Pellicle 이미징 연구** 김영웅[1], 우동곤[1], 장용주[2], 위성주[1], 안진호[1,2,3] *[1]한양대학교 신소재공학과, [2]한양대학교 나노반도체공학과, [3]나노과학기술연구소*